APR 1 2 2002

INFORMATION DISPLESURE CITATION
IN AN APPLICATION

(Use several sheets if necessary)

Docket Number 509982000100

Application Number 09/770,997

Applicant

Xinhui NIU and Nickhil JAKATDAR

Filing Date January 25, 2001

Group Art Unit 2621 2877

Mailing Date

April 9, 2002

## **U.S. PATENT DOCUMENTS**

Examiner Initials	Ref. No.	Date	Document No.	Name	Class	Subclass	Filing Date If Appropriate
(W)	1.	7/21/92	5,131,752	Yu et al.			
W	2.	11/17/92	5,164,790	McNeil et al.			
W	3.	3/4/97	5,607,800	Ziger	F	ECEIVE	<u> </u>
QV	4.	4/14/98	5,739,909	Blayo et al.			
au	5.	11/10/98	5,835,225	Thakur	A	PR 1 7 2002	
Qui	6.	2/2/99	5,867,276	McNeil et al.	Techn	Ology Contor o	600
()AV	7.	10/5/99	5,963,329	Conrad et al.		Technology Center 20	

## FOREIGN PATENT DOCUMENTS

Examiner Initials	Ref. No.	Date	Document No.	Country	Class	Subclass	Trans YES	lation NO

	,	OTHER DOCUMENTS (including author, title, Date, Pertinent Pages, Etc.)		
Examiner	Ŕef.	Title		
Initials	No.			
alle	8. ′	N. W. Ashcroft et al., "Solid State Physics", Saunders College Philadelphia, 1976, pgs. 133-135.		
QM	9	R. M. A. Azzam et al., "Ellipsometry and Polarized Light", Elsevier Science B. V., 1987, book.		
aw	10. ~	Ch. M. Bishop, "Neural Networks for Pattern Recognition", Ch. 4, 1995, pp. 117-161.		
and	11	S. Bushman et al., "Scatterometry Measurements for Process Monitoring of Gate Etch", AEC/APC Workshop IX, Sematech, Sept. 20-24, 1997, pp. 148-158.		
aw	12	G. Granet et al., "Efficient implementation of the coupled-wave method for metallic lamellar in TM polarization", J. Opt. Soc. Am. vol. 13, no. 5, May 1996, pp. 1019-1023.		
	13. —	O. S. Heavens, "Optical Properties of Thin Solid Films", Dover Publications, Inc. 1955, book.		
Ü	14.	P. Lalanne et al., "Highly improved convergence of the coupled-wave method for TM polarization", J. Opt. Soc. Am. vol. 13, no. 4, April 1996, pp. 779-784.		
	15.	L. Li et al., "Convergence of the coupled-wave method for metallic lamellar diffraction gratings", J. Opt. Soc. Am. vol. 10, no. 6, June 1993, pp. 1184-1189.		

EXAMINER:

DATE CONSIDERED:

27 July 2004

EXAMINER: Initial if citation considered, whether or not the citation conforms with MPEP 609. Draw a line through the citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.

PTO/SB/ 08 (2-92) sf-1279782 Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

OTP E 300 -

Form PTO-1449 INFORMATION SURE CITATION

Docket Number 509982000100

Application Number 09/770,997

TION SURGESSURE CITATION
IN AN APPLICATION

(Use several sheets if necessary)

Xinhui NIU and Nickhil JAKATDAR

Filing Date January 25, 2001

Group Art Unit 2621 28 77

Mailing Date

**Applicant** 

April 9, 2002

ay	16.	D. Maystre; "A new general integral theory for dielectric coated gratings", J. of Opt. Soc. of Amer. vol. 68 (4), Apr. 78, pp. 189-194.
aw	ر 17.	M. G. Moharam et al., "Rigorous coupled-wave analysis of planar-grating diffraction", J. Opt. Soc. Am. vol. 71, no. 7/July 1981, pp. 811-818.
aw	18.	M. G. Moharam et al., "Formulation for stable and efficient implementation of the rigorous coupled-wave analysis of binary gratings", J. Opt. Soc. Am. vol. 12, no. 5, May 1995, pp. 1068-1076.
W	19.	Moharam et al., "Stable implementation of the rigorous coupled-wave analysis for surface - relief gratings: enhanced transmittance matrix approach", J. Opt. Soc. Am. vol. 12, no. 5, May 1995, pp. 1077-1086.
ay	<b>2</b> 0.	M. Neviere et al., "Systematic Study of Resonances of Holographic Thin Film Couplers", Optics Com. vol. 9 (1), 1973, pp. 205-209.
We	21.	A. R. Neureuther et al., "Numerical Methods for the Analysis of Scattering from Nonplanar Periodic Structures", URSI Symposium on Electromag. Waves, 1969, pp. 185-188.
	22. ′	W. H. Press et al., "Numerical Recipes in C", Art of Scien. Computing 2nd Ed., 1986, pp. 29-38.
W	23.	J. A. Rice, "Mathematical Statistics and Data Analysis" sec. ed., ch. 14, Duxbury Press, 1995, pp. 507-570.

RECEIVED

APR 1 7 2002

Technology Center 2600

EXAMINER:

DATE CONSIDERED:

27 Jun 2004

EXAMINER: Initial if citation considered, whether or not the citation conforms with MPEP 609. Draw a line through the citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.